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APPLICATION NO	NO. FILING DATE		FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/050,334	10/050,334 01/15/2002		Vishnu K. Agarwal	MI22-1913 7861		
21567	7590	04/24/2006		EXAMINER		
	ST. JOHN	P.S. UE, SUITE 1300	NGUYEN, TUAN H			
	E, WA 992		ART UNIT	PAPER NUMBER		
			2813			
			DATE MAII ED: 04/24/2006			

Please find below and/or attached an Office communication concerning this application or proceeding.

					R			
		Application	ı No.	Applicant(s)	1			
	Office Astinu Ossus see	10/050,334	Į.	AGARWAL ET AL.				
	Office Action Summary	Examiner		Art Unit				
	71. 4441 100 0 475	Tuan H. Ng		2813				
Period fo	- The MAILING DATE of this communication app or Reply	pears on the	cover sheet with the c	orrespondence address	5			
WHIC - Exte after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DONA INSIDE OF THE MAILING DONA IN THE MAILING THE M	ATE OF THI 136(a). In no ever will apply and will b. cause the applic	S COMMUNICATION It, however, may a reply be time expire SIX (6) MONTHS from the lation to become ABANDONE	I. sely filed the mailing date of this commun O (35 U S C S 133)				
Status								
1)⊠	Responsive to communication(s) filed on 15 Fe	ebruary 200	5 .					
		s action is no						
3)	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is							
	closed in accordance with the practice under E	Ex parte Qua	yle, 1935 C.D. 11, 45	3 O.G. 213.				
Dispositi	ion of Claims							
5)□ 6)⊠ 7)□	Claim(s) 22-24,26,28 and 29 is/are pending in 4a) Of the above claim(s) is/are withdraw Claim(s) is/are allowed. Claim(s) 22-24,26,28 and 29 is/are rejected. Claim(s) is/are objected to. Claim(s) are subject to restriction and/o	wn from con	sideration.					
Applicati	ion Papers							
9) 10)	The specification is objected to by the Examine The drawing(s) filed on is/are: a) accomplicant may not request that any objection to the Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the Example.	epted or b) drawing(s) be tion is required	held in abeyance. See d if the drawing(s) is obj	e 37 CFR 1.85(a). ected to. See 37 CFR 1.1				
Priority ι	ınder 35 U.S.C. § 119							
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 								
Attachmen	t(s)							
	e of References Cited (PTO-892)	4	4) Interview Summary					
3) 🔯 Inforr	e of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08) r No(s)/Mail Date 2/28/06, 2/14/06		Paper No(s)/Mail Da 5) Notice of Informal Pa 6) Other:	te atent Application (PTO-152)				

DETAILED ACTION

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 22-24, 28, 29 are rejected under 35 U.S.C. 103(a) as being unpatentable over Chi in view of Schugraf et al. (cited refs.).

Chi, fig. 4 and related text on col. 2-3 discloses substantially the claimed capacitor construction including an opening 113 in an insulative layer over a substrate 101; an undoped HSG polysilicon layer 203 over the sides of the opening but not over the bottom wherein the polysilicon comprises spaced apart grains (fig. 2, col 2, line 41 to col. 3, line 12); a conformal first capacitor electrode 301 of doped polysilicon on the HSG polysilicon 203 but not comprising the HSG polysilicon layer as part of the first electrode, the first electrode 301 being sufficiently thin that the first electrode has a rugged outer surface with an outer surface area per unit area greater than an outer surface area per unit area of the substrate underlying the first electrode (col. 3, third and fourth paragraphs); a capacitor dielectric layer 401 on the first electrode 301; and a second electrode 403 over the dielectric layer 401.

Chi fails to teach the use of TiN for forming the first electrode 301.

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Schugraf et al. in a related electrode structure for use on an integrated circuit as shown in figs. 4-5 and text on col. 4, teaches the use of either doped polysilicon or TiN for electrode 30 (col. 4, lines 34-56).

It would have been obvious to one having ordinary skill in the art at the time the invention was made to have replaced polysilicon with TiN as suggested by Schugraf et al. in forming first capacitor electrode in Chi since the substitution of art recognized equivalence as suggested by Schugraf et al. is within level of those skilled in the art.

Claim 26 is rejected under 35 U.S.C. 103(a) as being unpatentable over Chi in view of Schugraf et al. as applied to claims 22-24 above, and further in view of Hwang et al..

The combination of Chi and Schugraf et al. fails to teach dielectric layer comprises high dielectric constant material.

Hwang et al. in a related capacitor structure teaches the use of high k material including Ta₂O₅, Al₂O₃, HfO₂, BST, ST for increasing in cell capacitance (Background of the invention, col. 1, lines 25-31).

It would have been obvious to one having ordinary skill in the art at a the time the invention was made to have used the well-known high k material as suggested by Hwang et al. in the combination teachings of Chi and Schugraf et al. for further increase in capacitance.

With respect to ZrO₂ and WO₃, since they are well-known to have high dielectric constant and commercial available, it would have been obvious to those skilled in the art to use them as a dielectric in capacitor structure.

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The prior art made of record and not relied upon is considered pertinent to applicant's disclosure. Raaijmaker et al., col. 4, lines 17-49 discloses the use of high k dielectric material in capacitor structure including ZrO₂; and Kawakita et al. discloses the high k material including WO₃ for use in capacitor.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Tuan H. Nguyen whose telephone number is 571-272-1694. The examiner can normally be reached on 9AM-5:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead Jr. can be reached on 571-272-1702. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Tuan H. Nguyen
Primary Examiner
Art Unit 2813